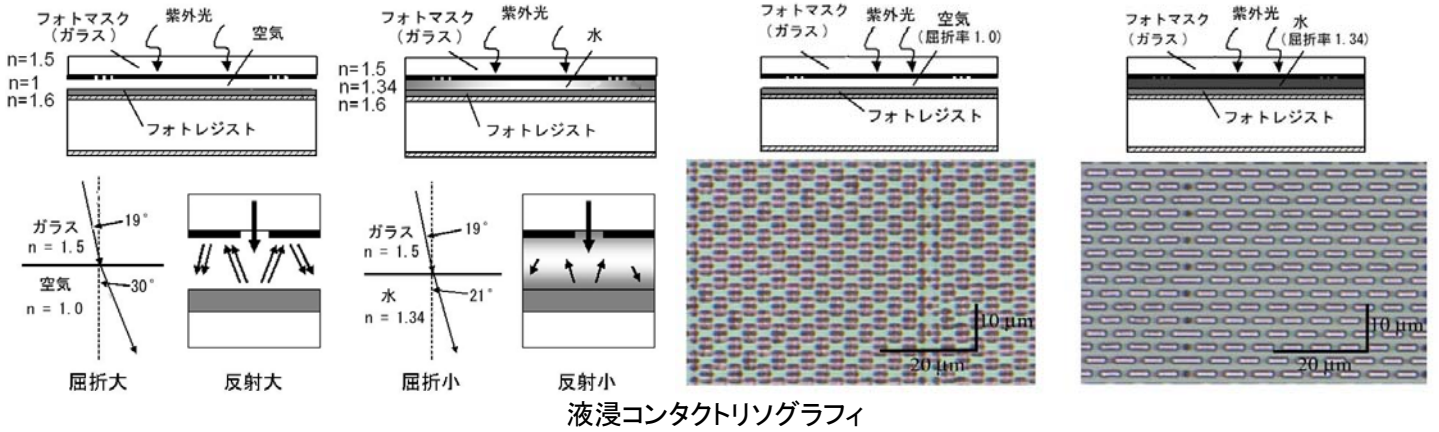
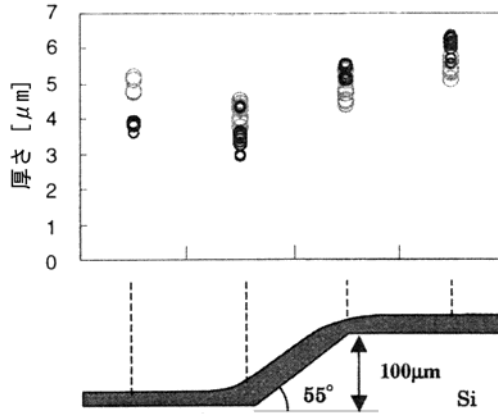
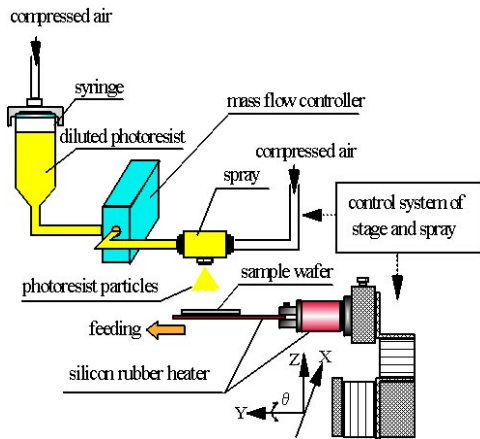


パターニング



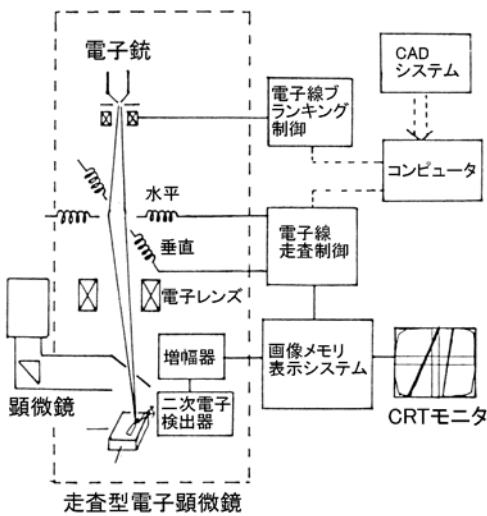
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レジストのスプレーコーティング

ウシオ電機

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